



Variable Pumping Control for Low Power Microfluidic Chip Cooling

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STREAMS

Smart Technologies for eneRgy Efficient Active
cooling in Advanced Microelectronic Systems



Introduction

Microelectronic modules increase in power density

→ liquid cooling required to maintain acceptable chip temperatures

→ μ channels:

low thermal resistance – fabrication using MEMS technology - easy integration in system.

increased pressure drop compared to larger scale cold plates.

→ pressure drop reduction: optimal design of flow distribution

→ limited energy in portable applications, power consumption by the cooling system should be minimized.

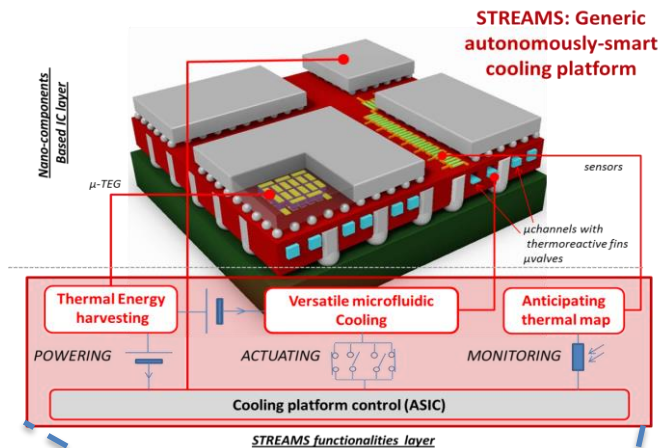
→ flow rate reduction by adapting the pumping power





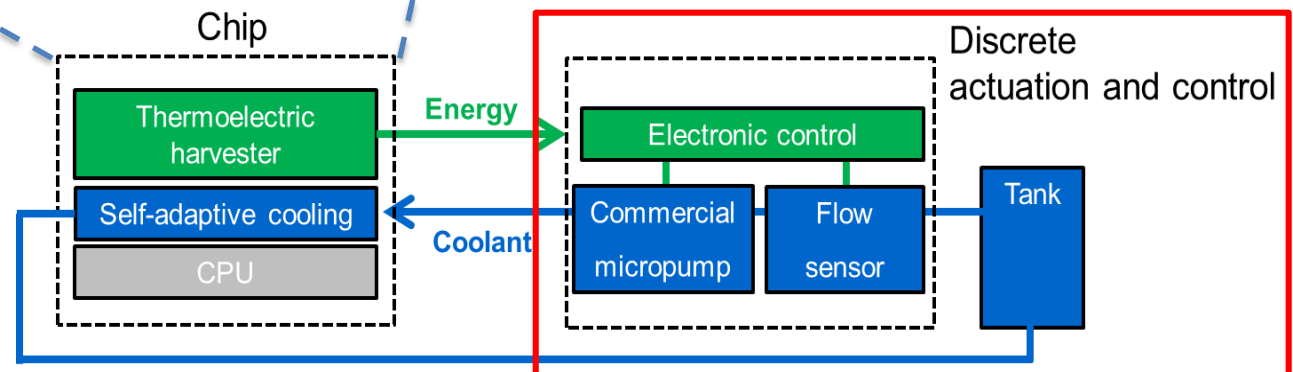
Introduction

Optimization of the system cooling based on μ fluidic channels to minimize the power consumption by using variable pumping power.



Energy efficient controllable pump module

- Pump
- Sensors: temperature, pressure and flow
- electronics drive





concept of the pump module

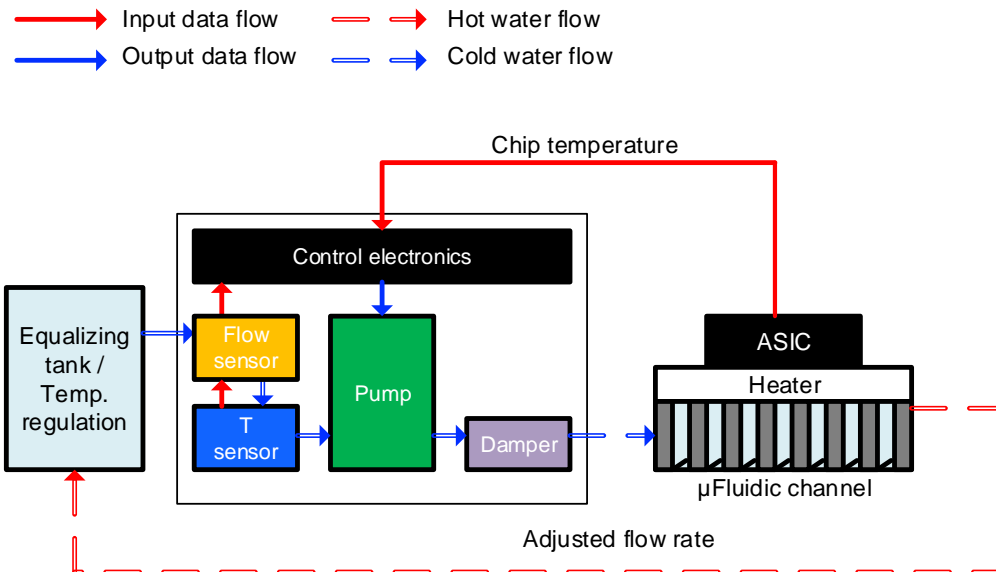
- **Constraints and parameters for the μ Fluidic design**

Max. surface temperature 85°C and inlet temperature 50°C

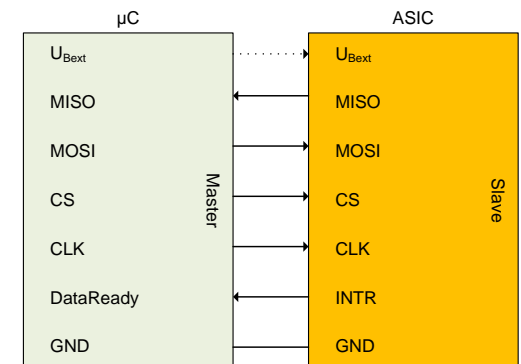
Total pressure drop 10 kPa

- **Pump module design :**

closed loop regulation \rightarrow realized as a test bench during configuration phase



SPI interface





The membrane pump

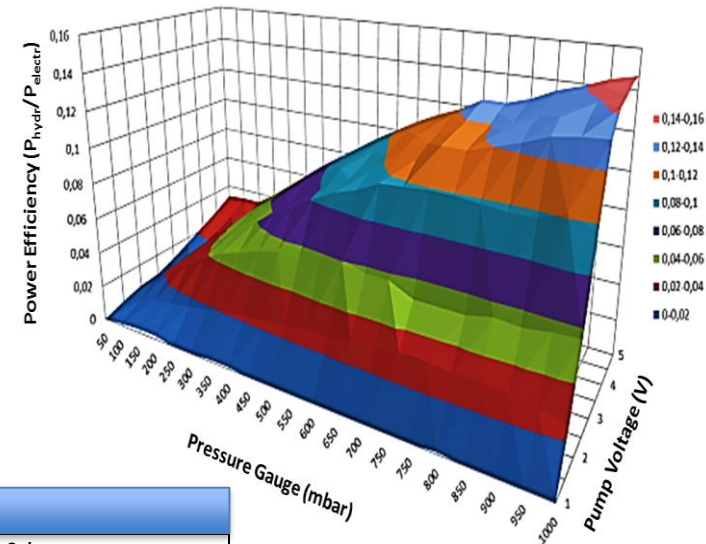
- oscillating displacement (eccentric system)
- operates against pressure drop up to 1 bar (10 kPa)
- adjustable pumping power: proportional to the resulting flow rate.
- maximum flow rate of around 50 ml/min



KNF Neuberger

$$\text{Pump efficiency} = \frac{P_{\text{hydraulic}}}{P_{\text{pump}}}$$

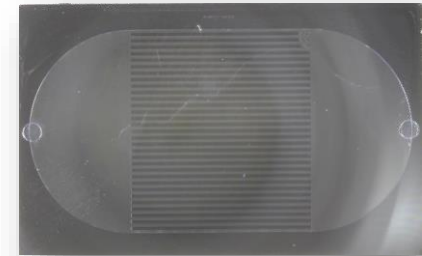
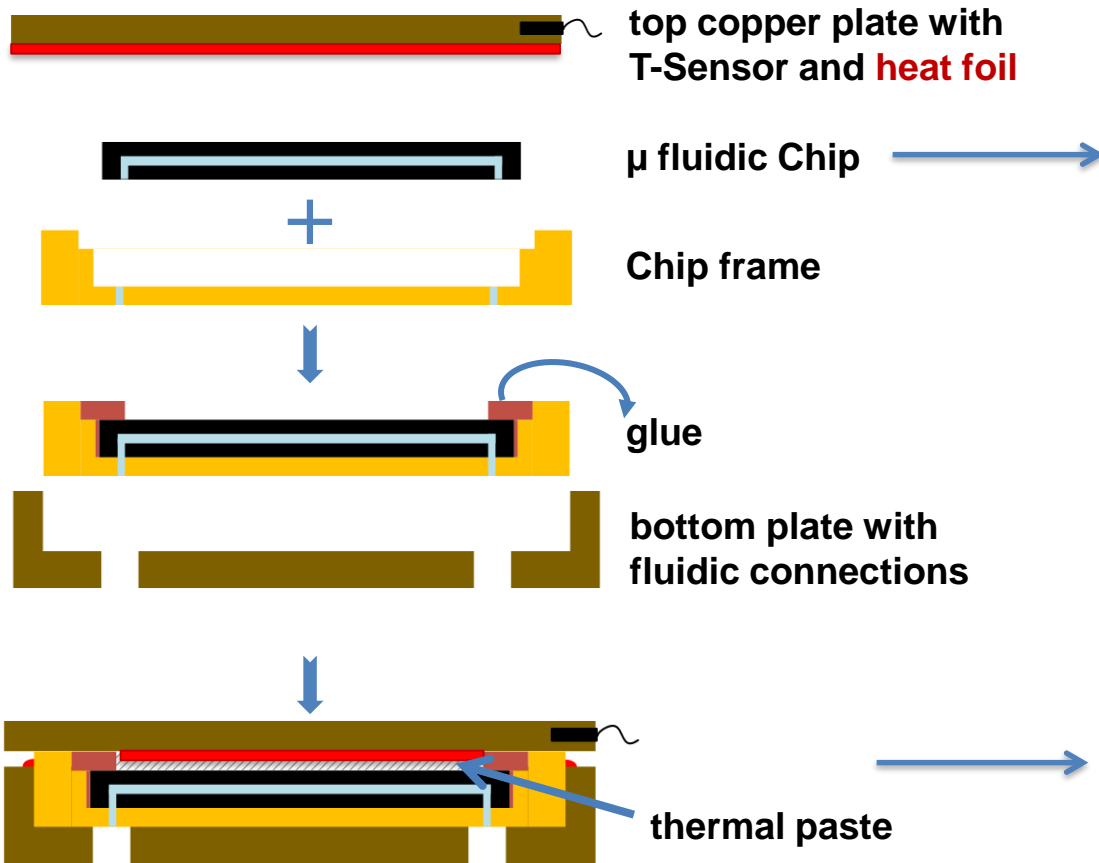
$$P_{\text{hydraulic}} = Q \cdot \Delta P \text{ (across the microfluidic structure)}$$



Specification	NF 60	NF 25	NF 5
Type	Micro diaphragm, brushless DC motor, self-suctioning at 0.3 bar		
Materials	PP (head), EPDM (valves, diaphragms)		
Control voltage	0.3-5 V DC		
Input voltage	12 V		
Pressure drop	Max. 1 bar		
Flow rate range	Max. 600 ml/min	250 ml/min	60 ml/min
Power consumption	18 W	2.6 W	1.5 W



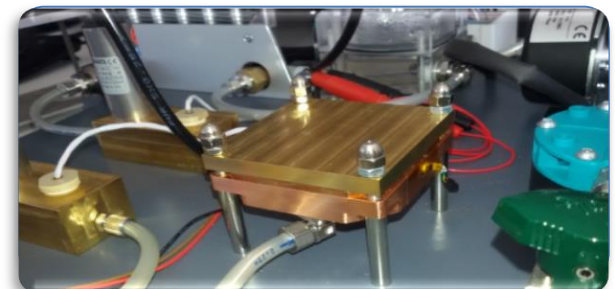
μ fluidic structure



20mm

μ fluidic Chip:

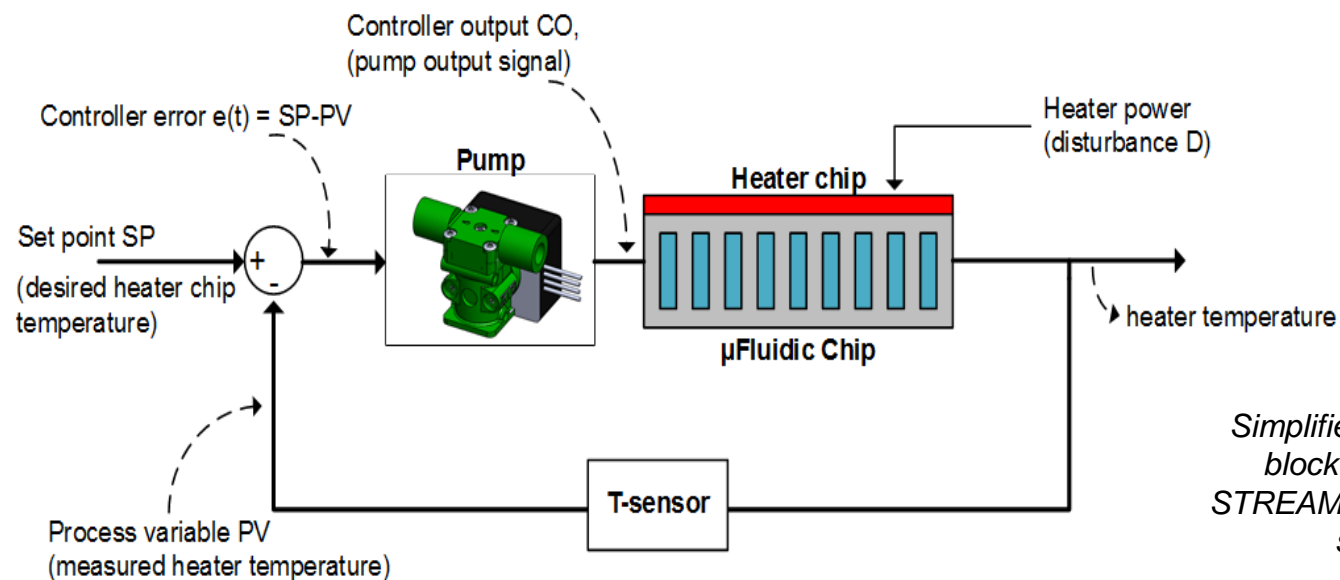
- 32 channels in parallel
- with a $200 \times 200 \mu\text{m}^2$ cross section
- and $150 \mu\text{m}$ glass for the cover with inlet and outlet





Water cooling system

- Variable pumping power on micro fluidic channels can minimize the power consumption.
- Parameterization is done by calculating the step response
- control based on temperature signals



*Simplified control loop
block diagram for
STREAMS water cooling
system*



Step response @ Heater power variation

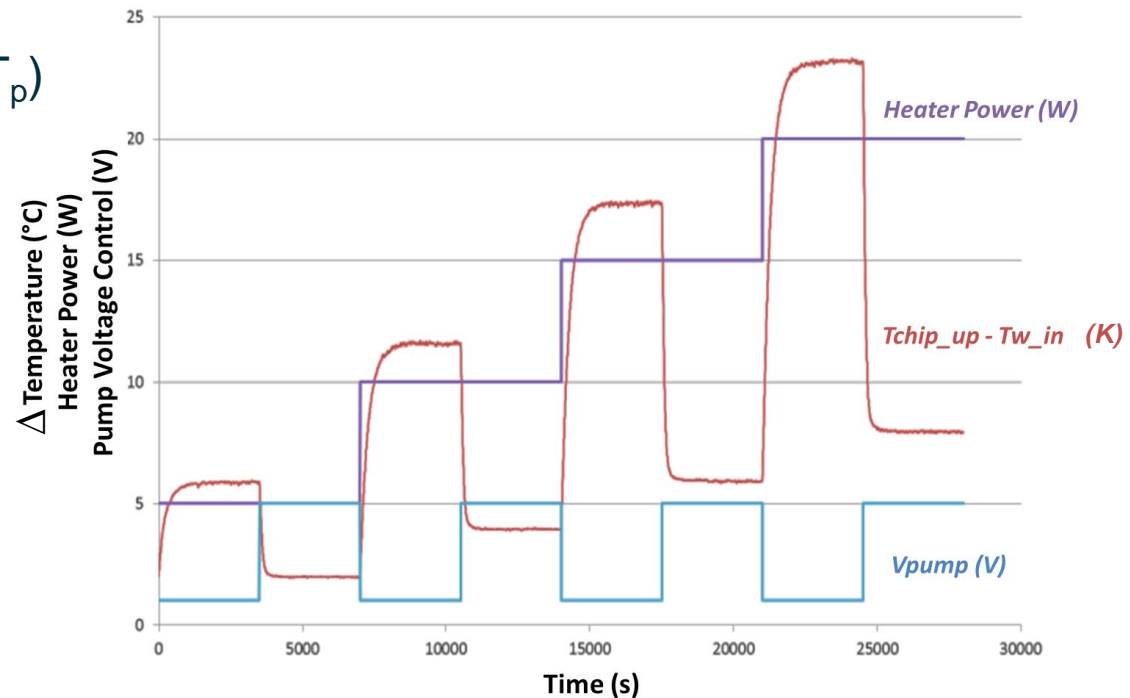
- Pump voltage increased step by step after steady-state at different heating power
- experimental determination of :

process gain $K_p = PV_2 - PV_1$

process time constant (T_p)

and dead time (θ_p).

- $K_p = \frac{PV_2 - PV_1}{CO_2 - CO_1} \cdot CO_{range}$
- $T_p = t_{0,63PV2} - t_{start}$
- $\theta_p = \text{dead time} = 5 \text{ s}$

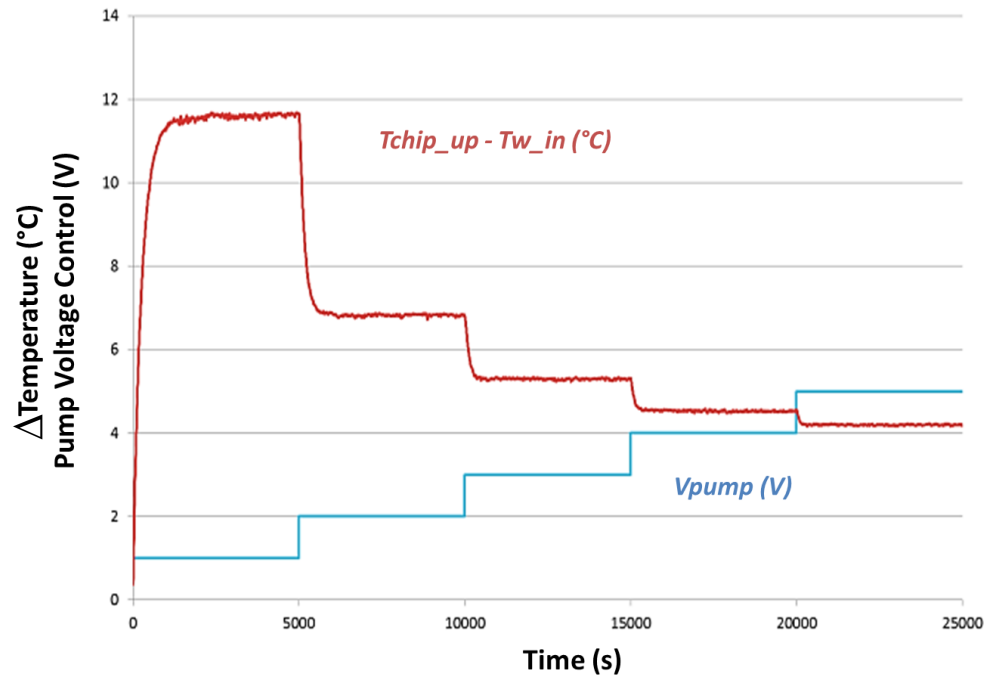




Step response @ Pump voltage variation

Non-linear system

- Equal Controller Output CO step doesn't result in equal process variable PV response
- differences in calculated controller gain K_p for each operation level



Non-linear system : Temperature progression curve of the step test during open loop modus ($T_{chip} - T_{water}$) at 10 W heater power



Construction of the controller

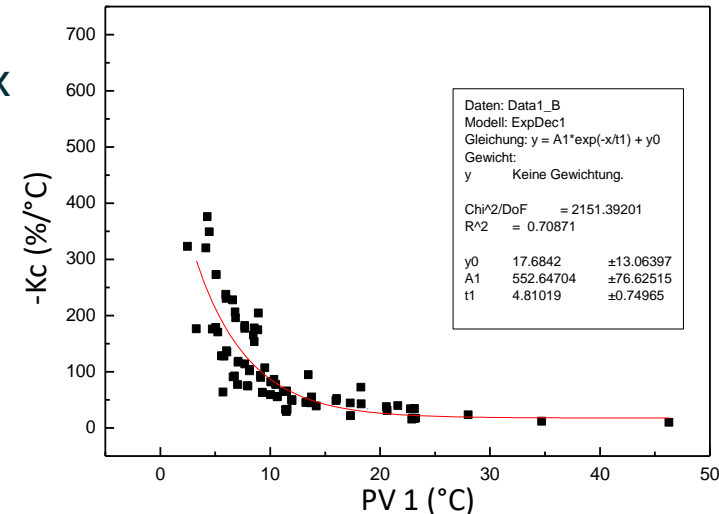
$$\text{Controller output } CO = K_p e(t) + \frac{K_c}{T_i} \int e(t) dt$$

$$\text{Closed loop time constant } T_c = |0.1 T_p, 0.8 \theta_p|_{\max}$$

$$\text{Controller gain } K_c = \frac{1}{K_p} \frac{T_p}{(\theta_p + T_c)}$$

$$\text{and Reset time } T_i = T_p$$

$$\text{non linear model: } -K_c = f(T_{chip} - T_{water})$$



Exponential dependency between controller gain and process variable

Solution: gain scheduling

→ controller gain depends on the temperature set point range

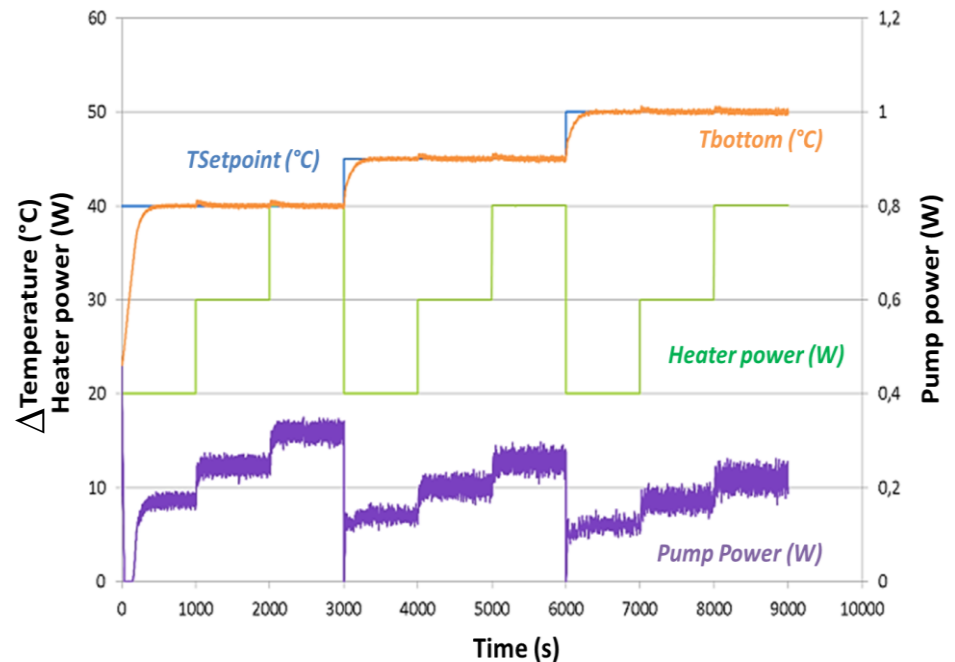
→ Parameter values have to be adapted, depending on system

- Anti wind-up logic $\int e(t) = \frac{T_i}{K_c} (CO_{desired} - K_c e(t))$



Results with PWM

- Reduction of electrical power consumption: implementation of PWM
The pump is turned on and off in certain frequency and duration by a PWM controller loop while the voltage output control is kept constant (5 V)
- Reduction of the average power consumption up to 50%
- Hydraulic power decreases with the increase of the allowed maximum chip temperature

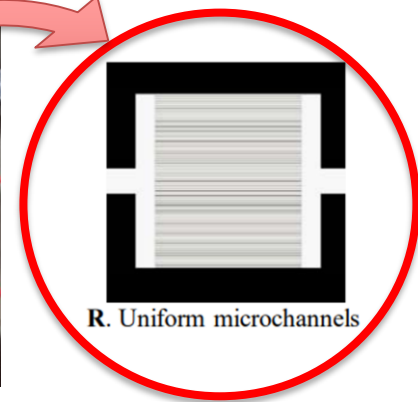
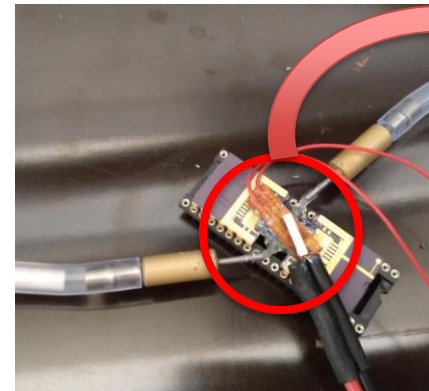


Pump control with Puls Width Modulation



Experimental conditions (Lleida)

Validation on a silicon microchannel based cooling device



Channel dimension
 $100 \times 100 \mu\text{m}^2$

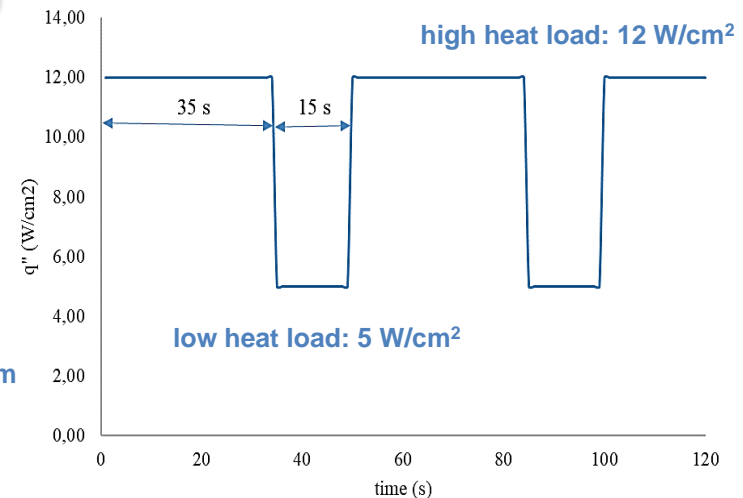
Comparison:

- cooling device with variable flow rate
- scenario of constant flow

under same load

- μ channel Inlet temperature: 25°C

temporal and non uniform
heat load

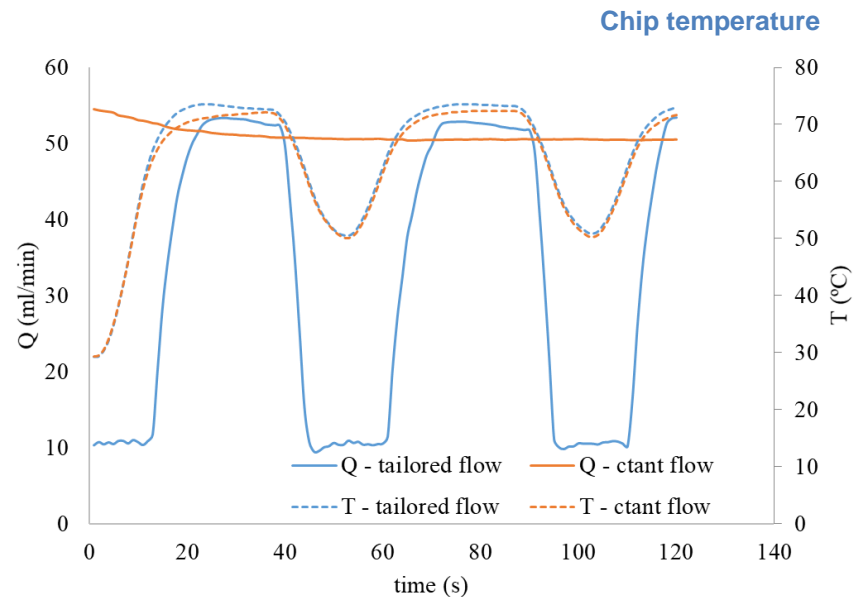




Experimental validation

- Temperature set point: 70°C
- Pump tailors the flow rate to maintain the maximum temperature limit.
high heat load → flow rate is increased
low heat load → flow rate is reduced

- Scenario of constant flow rate:
maximum flow achieved by the
variable pump is set to ensure a
temperature under the set point





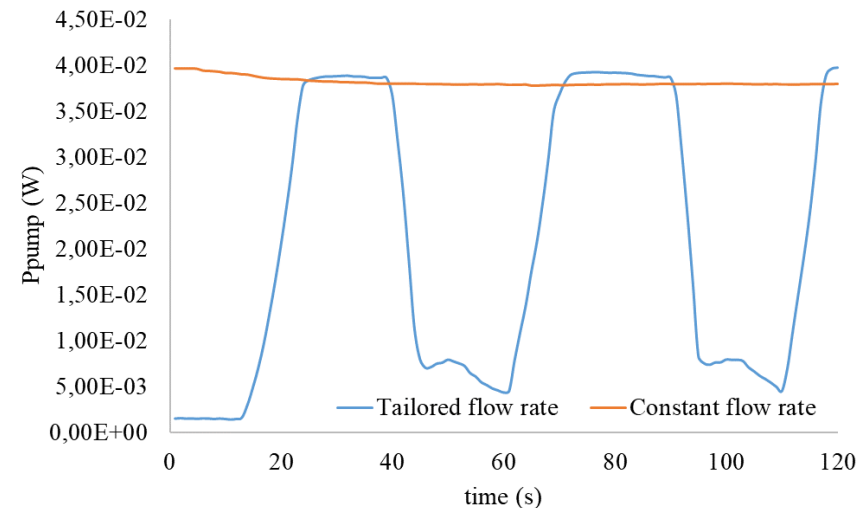
Conclusion

Pumping power (P_{pump}) of the device for both studied cases

A reduction of 46% is obtained for this heat load scenario

Additionally, the COP is 1.8 times higher when the flow rate is tailored.

$$COP = \frac{P_{\text{heater}}}{P_{\text{pump}}}$$



Use of a control algorithm with a variable pump

- 75% reduction of the pumping power @ constant chip temperature independent of the power dissipated
- reduction of thermal cycling
- potential higher reliability.

The overall increase of the COP is 84%.



Thank you for your attention!

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